

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of :
Ju Hyun KIM *et al.* : Confirmation No. -----
U.S. Patent Application No. ----- : Group Art Unit: -----
Filed: March 29, 2004 : Examiner: -----
For: METHOD FOR SEPARATING SAPPHIRE WAFER INTO CHIPS USING DRY-
ETCHING

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

Respectfully submitted,

LOWE HAUPTMAN GILMAN & BERNER, LLP

Benjamin J. Hauptman
Registration No. 29,310

1700 Diagonal Road, Suite 300
Alexandria, Virginia 22314
(703) 684-1111 BJH/klb
Facsimile: (703) 518-5499
Date: March 29, 2004

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.